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Substitute for form 1449B/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Complete If Known			
		Application Number	10/500,214		
		Filing Date	June 28, 2004		
		First Named Inventor	Takuya SUGAWARA		
		Art Unit	2812 2823		
Sheet	1	of	1	Examiner Name	Francine Young Michelle Estrada
				Attorney Docket Number	010986.55104US

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials [*]	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
AFR	AA	Y. AOKI, ET AL., "In Situ Substrate Surface Cleaning by Low-Energy Ion Bombardment for High Quality Thin Film Formation", J. Vac. Sci. Technol. A, March/April 1993, pp. 307-313, vol. 11 no. 2, American Vacuum Society	
AFR	AB	KATSUYUKI SEKINE, ET AL., "Silicon Nitride Film Growth for Advanced Gate Dielectric at Low Temperature Employing High-Density and low-Energy Ion Bombardment", J. Vac. Sci. Technol. A, September/October 1999, pp. 3129-3133, vol. 17, No. 5, American Vacuum Society	
AFR	AC	KOTARO MIYATANI, ET AL., "A New Plasma Dry Cleaning Method Applied to Contact and Gate Pre Cleaning", Extended Abstracts of the 2002 International Conference on Solid State Devices and Materials, 2002, pp. 196-197, Nagoya	
AFR	AD	N. SANO, ET AL., "Improvement of SiO ₂ /Si Interface by Low-Temperature Annealing in Wet Atmosphere", Appl. Phys. Lett., April 17, 1995, pp. 2107-2109, vol. 66, no. 16, American Institute of Physics	
AFR	AE	D. TCHIKATILOV, ET AL., "Improvement of SiGe Oxide Grown by Electron Cyclotron Resonance Using H ₂ O Vapor Annealing", Appl. Phys. Lett., October 21, 1996, pp. 2578-2580, vol. 69, no. 17, American Institute of Physics	
AFR	AF	TAKUYA SUGAWARA, ET AL., "Characterization of Ultra Thin Oxynitride Formed by Radical Nitridation with Slot Plane Antenna Plasma", Extended Abstracts of the 2002 International Conference on Solid Devices and Materials, 2002, pp. 714-715, Nagoya	
AFR	AG	AKIKO NARA, ET AL., "A Guideline for Accurate Two-Frequency Capacitance Measurement for ultra-Thin Gate Oxides", Extended Abstracts of the 2002 International Conference on Solid Devices and Materials, 2002, pp. 452-453, Sendai	
	AH	ATSUHIRO TSUKUNE, ET AL., "Cu Damascene Formation Process", The 8 th Semiconductor Process Symposium, September 20, 1999, pp. 74-76	
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AFR	AI	T. NGAL ET AL., "Improving SiO ₂ /SiGe Intface of SiGe p-metal-oxide-silicon field effect transistors using water vapor annealing", March 11, 2002, pp. 1773-1775	

Examiner Signature	Michelle Estrada	Date Considered	1/26/06
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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